

# Ion Beam Source IBS - 500

Ion source IBS-500 is a gas-discharge ion source, a hollow rectangular beam, the principle of operation is an accelerator with an anode layer (UAS).

The IBS-500 is designed to generate a linear flow of working gas ions with an energy of 300-2500 eV for a wide range of applications: ion cleaning, ion etching, ion polishing, ionic surface modification, assisted deposition

Directly this version is made according to the special requirements of the customer.



<b>Parameter</b>	<b>Value</b>
Supply voltage	600 – 4000 V
<i>Average ion energy is about half of the supply voltage</i>	
Maximum beam current	1250 mA
Beam shape	rectangular, hollow
Beam size (L x W x T)	474 x 42 x 5 mm
Working pressure range	0,001 – 10 Pa
Working gas	Argon
Coolant	distilled water
Weight no more	13 kg
Max. supply voltage	5500 V
Max. operating current	1000 mA
Max. working gas consumption	1,5-2,0 l / h
Minimum consumption of coolant	1 l / h

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## main dimensions, layout

